WHAT IS CLAIMED IS:

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- A method of making a transparent article comprising:
 providing a transparent, non-metallic substrate; and
- depositing upon the substrate, in sequence, a first dielectric film, a metal film, a second dielectric film of a metal oxide, and a protective film of silicon nitride having a thickness in the range of 10 to 150 Å.
 - 2. The method of claim 1 wherein the second dielectric film has an index of refraction essentially the same as that of silicon nitride.
- 3. The method of claim 2 wherein said second dielectric film and the silicon nitride film are contiguous.
- 4. The method of claim 1 wherein the combined thickness of said second dielectric film and the silicon nitride protective film ranges from about 250 to 400 Å.
- 5. The method of claim 4 wherein the combined thickness of said second dielectric film and said silicon nitride film is 300-350 Å.
 - 6. The method of claim 5 wherein the combined thickness of said second dielectric film and said silicon nitride film is 275-325 Å.
 - 7. The method of claim 1 wherein the metal film is silver.
 - 8. The method of claim 7, wherein the metal film of silver is 70 100 Å.
 - 9. The method of claim 1 wherein said metal oxide is zinc oxide or titanium dioxide.
 - 10. The method of claim 1, wherein the metal film is 70 100 Å.
 - 11. A method of making a transparent article comprising: providing a transparent, non-metallic substrate; and

depositing upon the substrate, in sequence, a dielectric film contiguous to the transparent substrate, a metal film, a shielding film contiguous to the metal film, a metal oxide film, and a protective film of from 10Å to 150 Å of silicon nitride contiguous to said metal oxide film.

- 5 12. The method of claim 11 wherein the metal film is silver.
 - 13. The method of claim 12, wherein the metal film of silver is 70 100 Å.
 - 14. The method of claim 11 wherein the index of refraction of the metal oxide film is essentially the same as silicon nitride.
- 15. The method of claim 11 wherein the shielding film and the metal oxide film are contiguous.
 - 16. The method of claim 11 wherein the metal oxide film is zinc oxide or titanium dioxide.
 - 17. The method of claim 11, wherein the metal film is 70 100 Å.
- 18. The method of claim 11 wherein the combined thickness of said second dielectric film and the silicon nitride protective film ranges from about 250 to 400 Å.